

Fig. 1

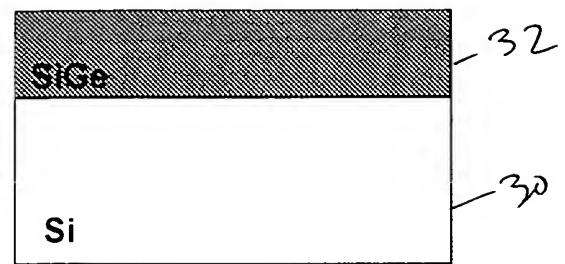


Fig. 2

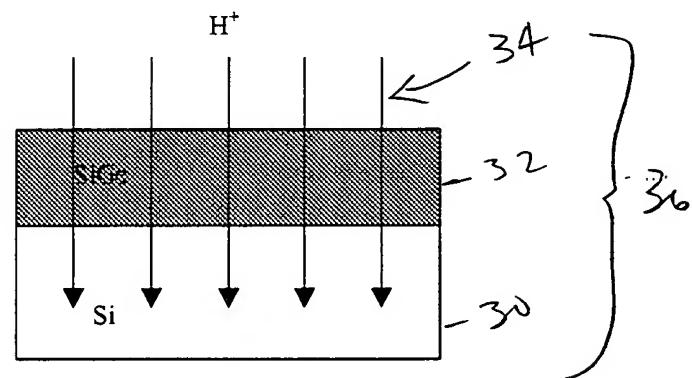


Fig. 3

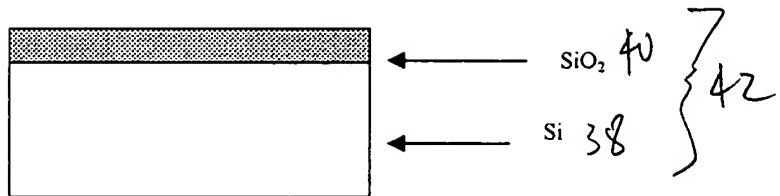


Fig. 4

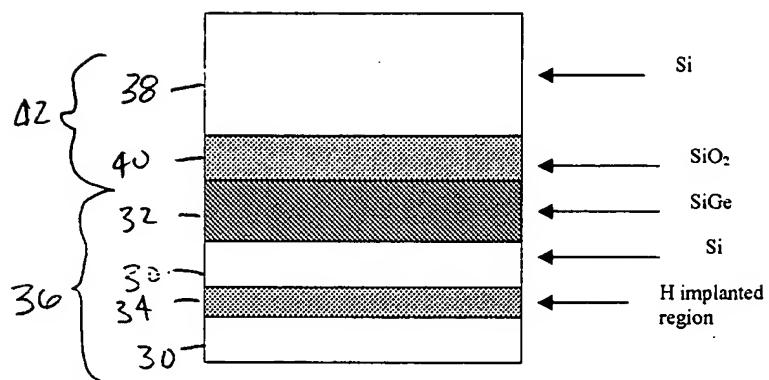


Fig. 5

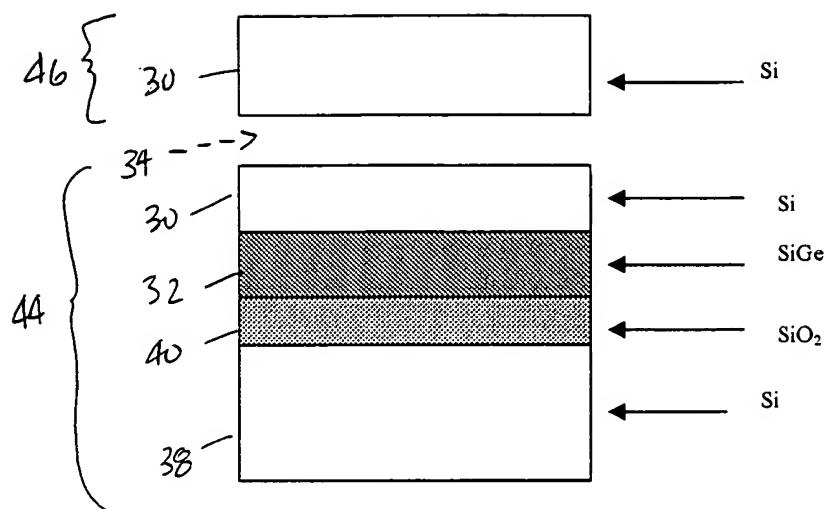


Fig. 6

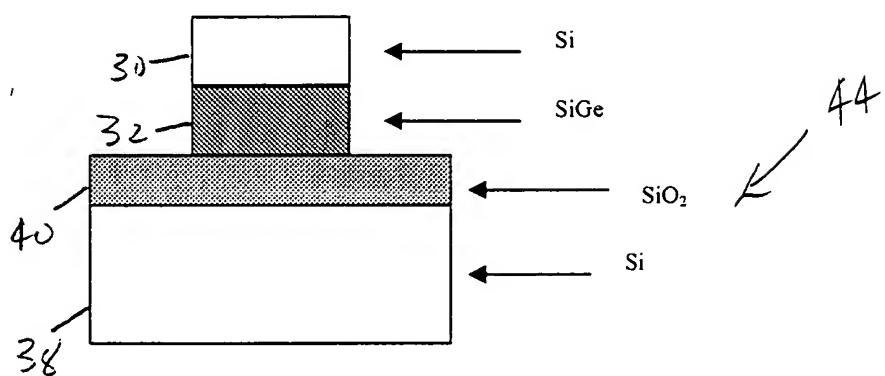


Fig. 7

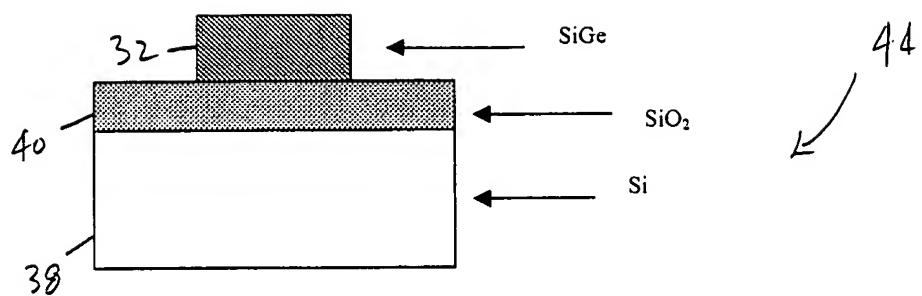


Fig. 8

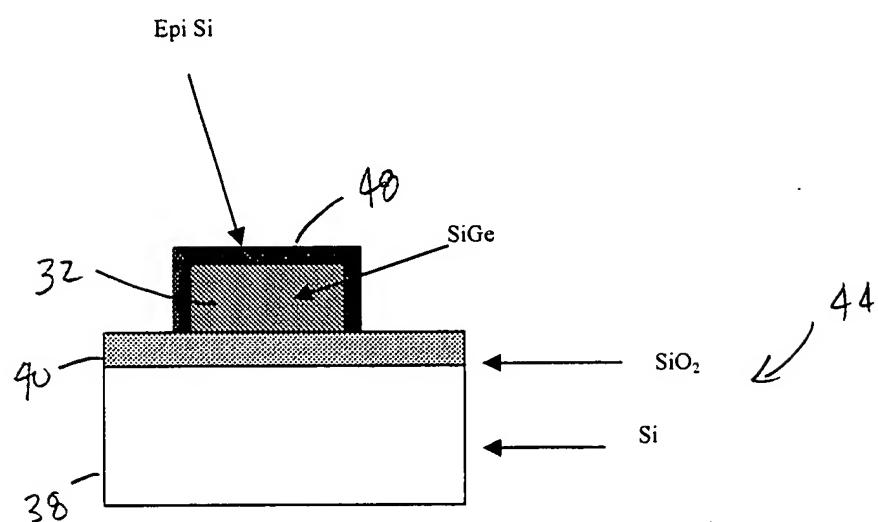


Fig. 9

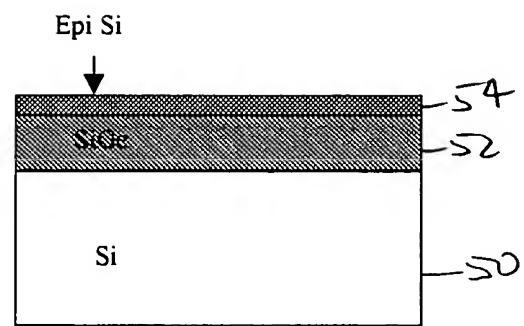


Fig. 10

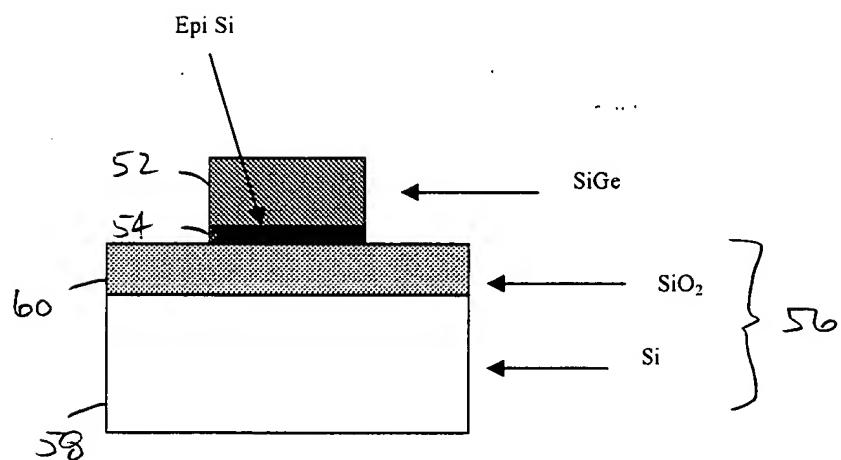


Fig. 11

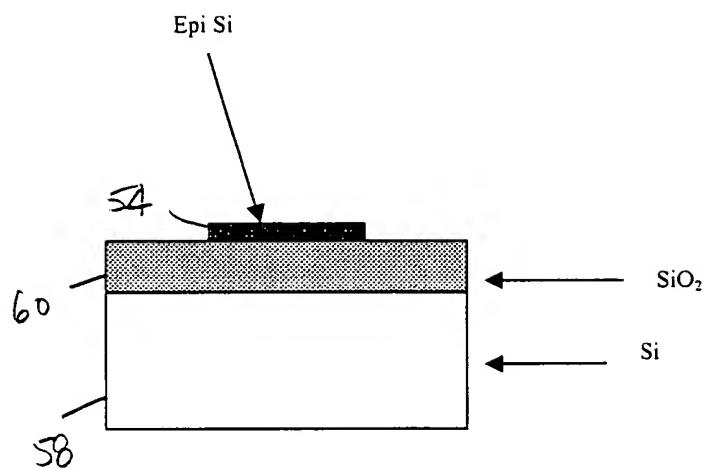


Fig. 12

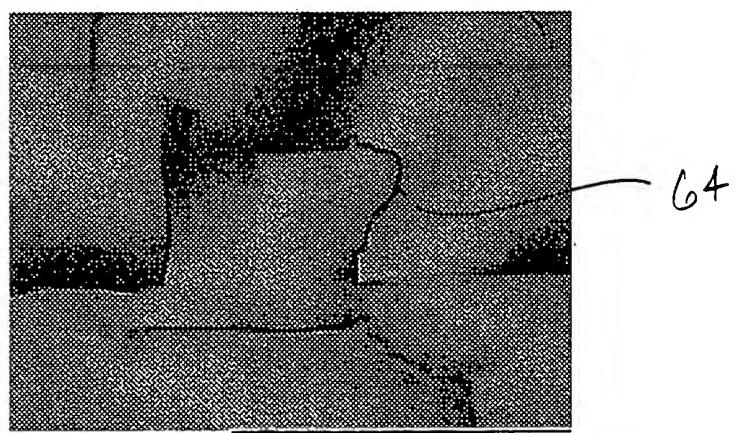


Fig. 13

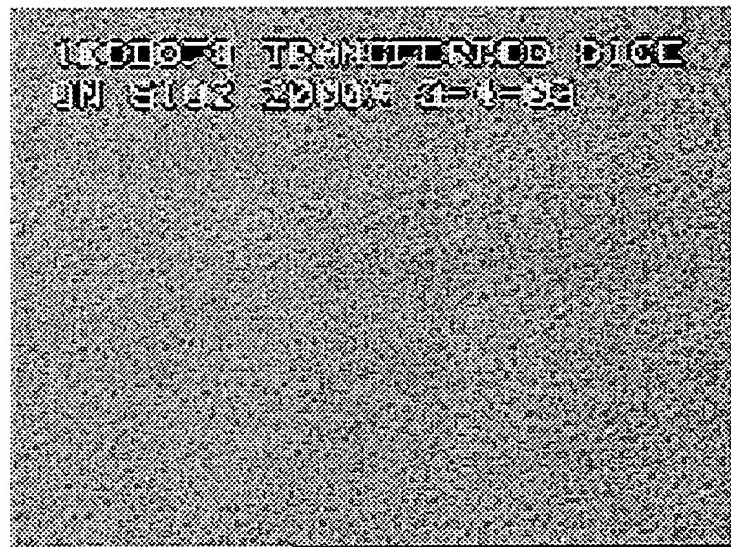


Fig. 14

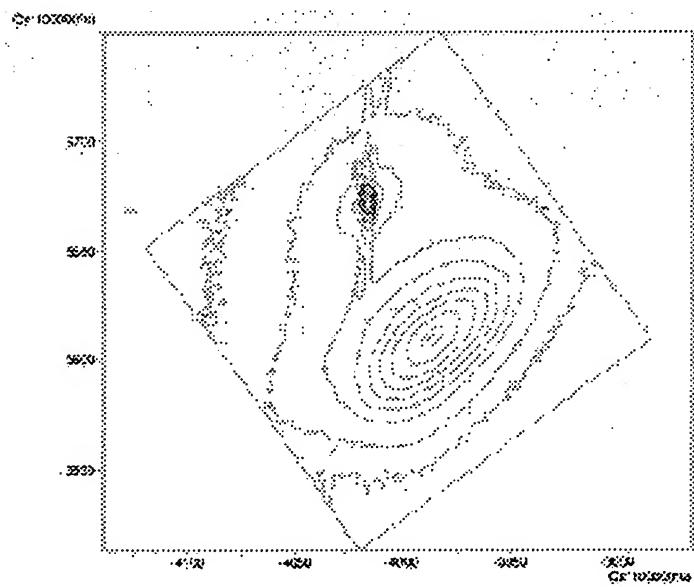


Fig. 15

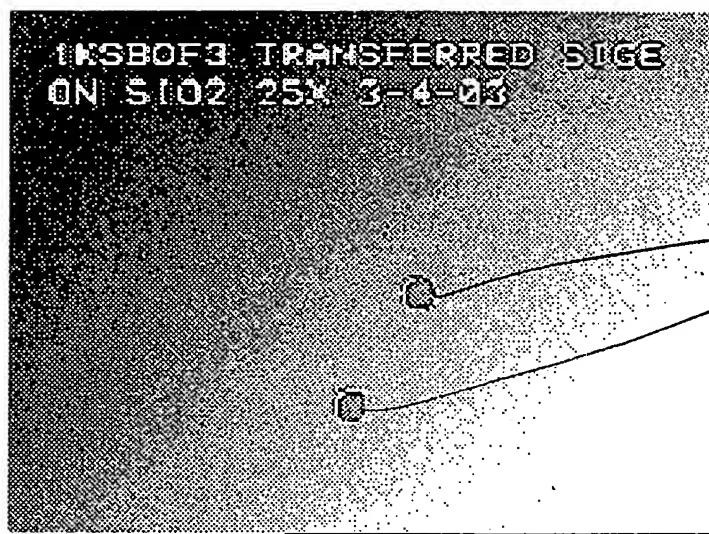


Fig. 16

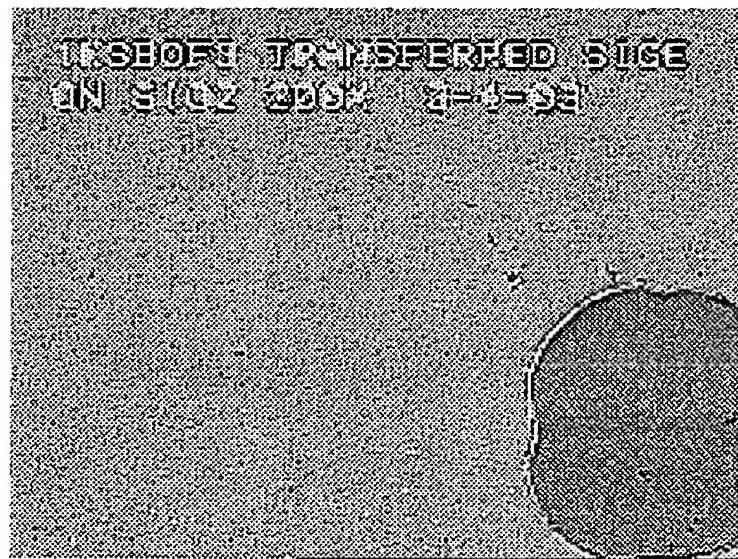


Fig. 17

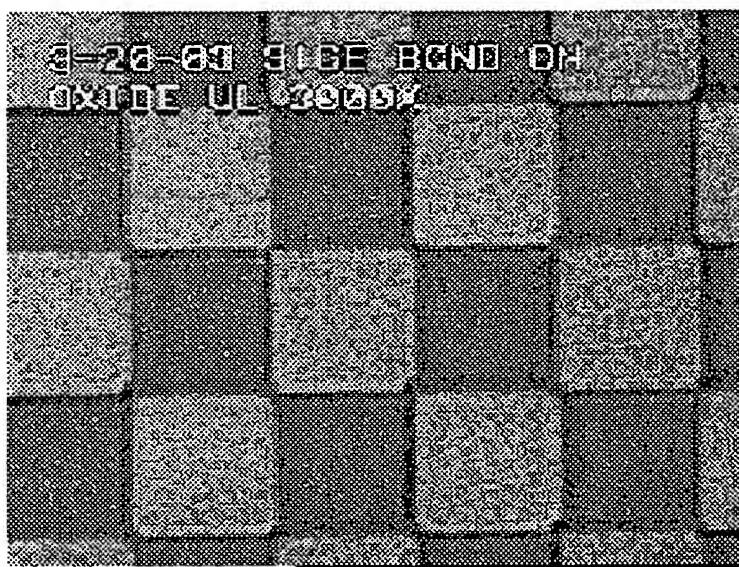


Fig. 18

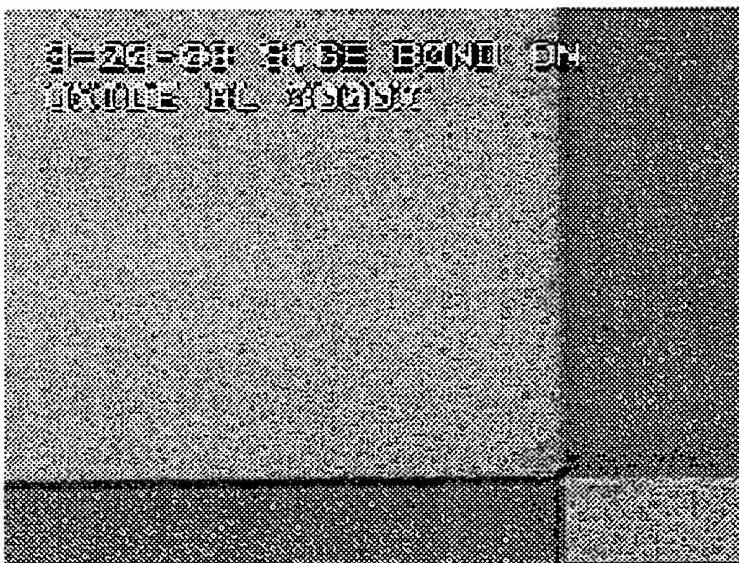


Fig. 19

**Relaxation of SiGe on SiO<sub>2</sub> after  
Wafer Splitting and Anneal**

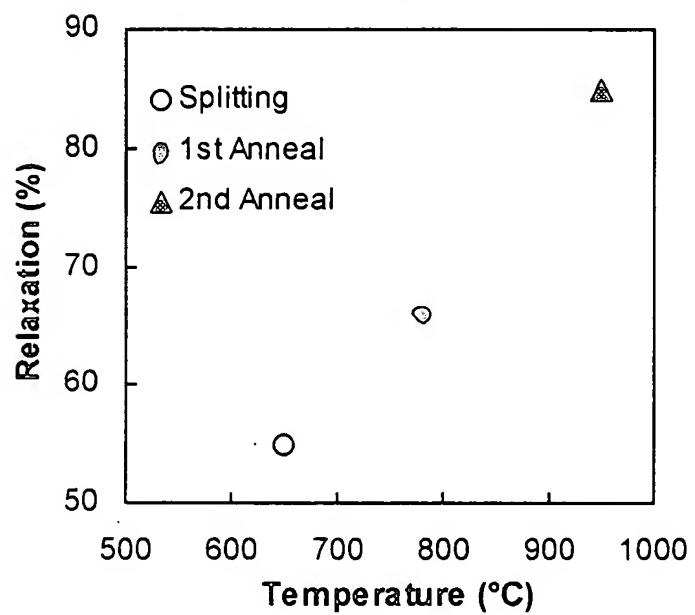


Fig. 20

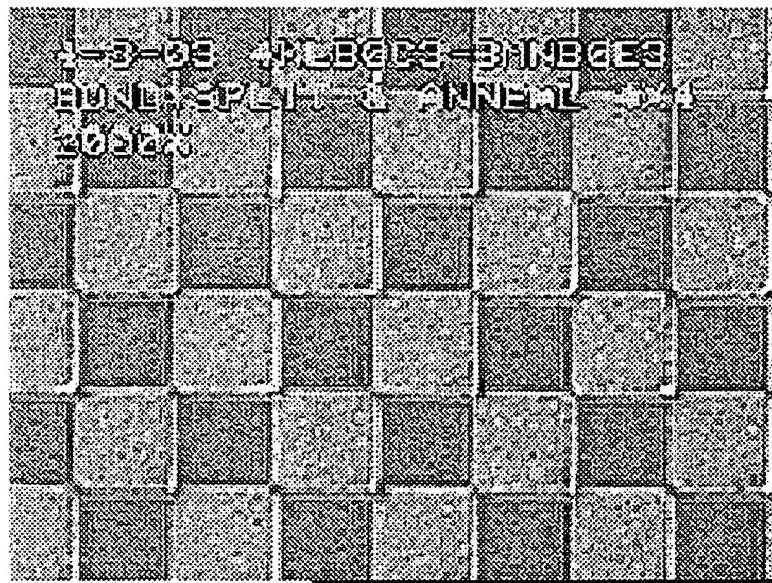


Fig. 21



Fig. 22

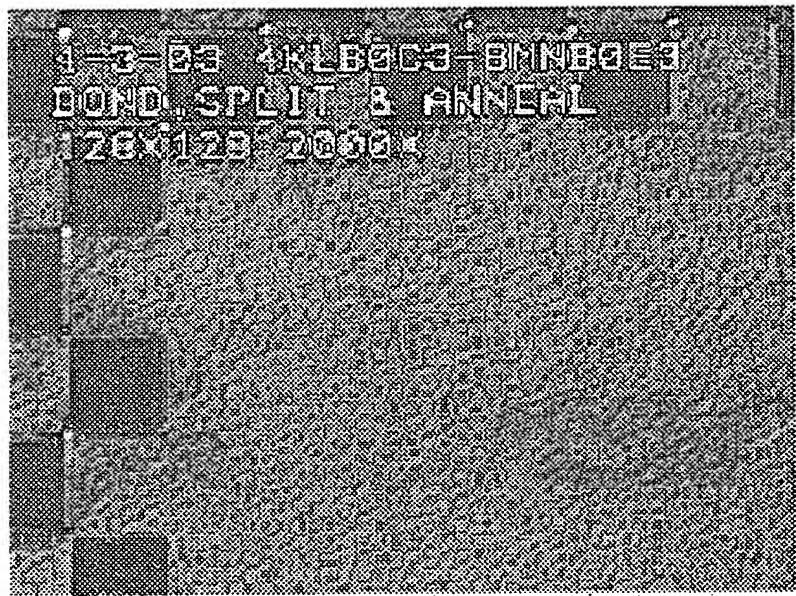


Fig. 23